



NVTH-350



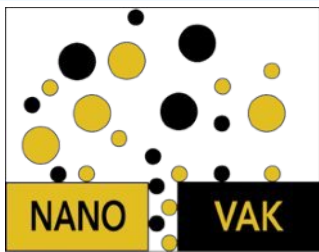
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Thermal Evaporator Systems

Box type Physical Vapor Deposition system is based on prismatic/cylindrical vacuum chambers. These systems have 2 – 4 thermal sources. Multi-layered thin films of two, three or four different materials can be prepared by NVTH system. NANOVAK® Thermal Evaporator Systems can be tailored to fit user desires in order to produce multilayered, nanosize metallic, oxide, fluoride or nitride films, such as Si, Al, Ti, SiO, Au, Ag, WO, BaF₂, MgF₂.

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Thermal Evaporator Systems



- Fully automatic computer control option, touch screen panel control with real time LCD displays
- Prismatic/cylindrical vacuum chamber made of SS304. 30/40/50/60 cm box size, clean electro-polished surfaces
- Front viewing window and rotatable shutter,
- Standard 1", QF, CF, ISO ports
- Internal lighting and baking of the system, internal baking option up to 120°C,
- 10-8 Torr base pressure level, 2x10⁻⁶ Torr vacuum level in 20 minutes
- Turbomolecular + Mechanical pump, cryo-pump and dry pump as desired,
- Wide range (1000 - 10⁻⁹ Torr) vacuum control and measurement system
- 50-700°C PID sample rotation-heating option
- 2-30 rpm adjustable sample rotation unit
- Sample surface cleaning option by RF plasma
- Automatic closed loop water cooling
- 0.1Å/s dual-channel precision thickness-rate measuring unit with 1-4 QCM's, with averaged value
- 2x2 channel, 12V - 200A sequential/co-evaporation thermal evaporation sources with voltage current power display
- Mass flow meter controlled gas inputs, isolation valves, chamber backfill with Ar or N₂ as desired
- 1.5 hour experiment cycle-time,
- The chamber remains under vacuum with isolation valve when not in use.
- Fully automated deposition of each layer of coatings
- 75x120 cm footprint, lockable wheels
- Easily passes through standard doors
- One year warranty for design, materials and workmanship